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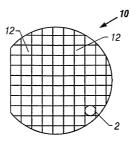


FIG. 1

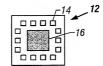
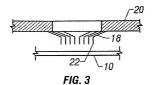


FIG. 2



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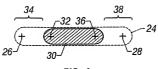
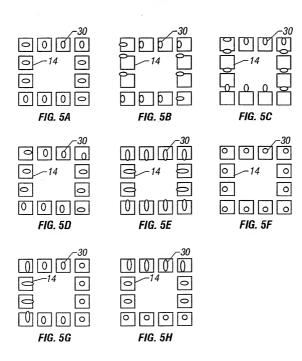


FIG. 4



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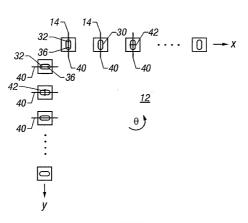


FIG. 6